An Artificial Neural Network Approach for Screening Test Escapes

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Outline

- Motivation
- Feature Generation
- Artificial Neural Networks
- Data Setup
- Experimental Results

Motivation

Test Escapes are chips that pass the entire test program but fail at system-level tests or in field

Machine Learning techniques have demonstrated promising results for predicting test escapes based on parametric production test data

Artificial Neural Networks have great potential and achieved higher performance in complicated tasks such as object / speech recognition

Features: Residual Vector

For a chip with N test measurements



 \mathbf{x}_{m} : N by 1 vector of measured values \mathbf{x}_{e} : N by 1 vector of expected values

Selecting the Expected Values x_e

- Mean of the wafer
 - produces feature set F_M
- Bilateral filtered spatial pattern of the wafer
 produces feature set F_B
- Median of the eight closest neighbors' values
 Produces feature set F_N

Each feature set is expressed as an N by 1 vector

F. Lin, C-K. Hsu, K-T. Cheng, "Feature Engineering with Canonical Analysis for Effective Statistical Tests Screening Test Escapes", ITC, 2014

Use of ANN for Test Escape Screening



Artificial Neural Networks

Input Features



The Autoencoder Model



700+ Recovered Features

The Autoencoder Model

- Unsupervised training
 - Train with only good chips in the training set
 - Find a set of bottleneck features that best represent the dataset of good chips
- Testing
 - Apply the *autoencoder* to a query chip and calculate the Euclidean distance between the input and output layers
 - Classify a chip as anomaly if the value is greater than a threshold

The Proposed Test Flow

• Standardize test data based on each wafer to remove wafer-to-wafer variations



Data Setup

Industrial Production Test Data

Training set: 200+ wafers Validation set: 200+ wafers Testing set: 200+ wafers 200+ parametric test items 1000+ chips per wafer

*Emulated Test Escapes 560 PPM

*F. Lin, C-K. Hsu, K-T. Cheng, "Feature Engineering with Canonical Analysis for Effective Statistical Tests Screening Test Escapes", ITC 2014 11

Comparison of Autoencoder Structures

More hidden layers may better capture the characteristics of the training set, but the captured characteristics does not necessarily expose test escapes as anomalies.



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Autoencoder with 1 Hidden Layer Performs Best at Target Region



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Comparison with Other Frameworks



F. Lin, C-K. Hsu, A. G. Busetto, and K-T. Cheng, "Pairwise proximity-based features for test escape screening", ICCAD 2015

Pairwise Proximity





Pairwise Proximity





Autoencoder Exposes More Test Escapes Than Other Frameworks



A Closer Look at Identified Test Escapes and Yield Losses



A Hybrid Framework May Improve the Classification Accuracy



Prediction Runtime Improvement

SVM on base and proximity features
 - 4.6 seconds per wafer

- Autoencoder Configuration
 - Caffe package from UC Berkeley
 - Nvidia GTX 980
 - 0.1 second per wafer
 - 46X speed up

Conclusion

- Autoencoder could identify more test escapes than the SVM framework using both base and proximity features, with significant runtime reduction
- Because of the unsupervised training process, a model that fits the training set better does not necessarily lead to a higher test escape detection rate. A validation process is needed to select the best model.
- Proposed autoencoder is a relatively simple ANN structure, several ANN design choices might be further optimized
 - e.g. activation function, cost function, solver for updating weights.